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Mapping Charge Carrier Density in Organic Thin-Film Transistors by Time-Resolved Photoluminescence Lifetime Studies

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Abstract

The device performance of organic transistors is strongly influenced by the charge carrier distribution. A range of factors effect this distribution, including injection barriers at the metal-semiconductor interface, the morphology of the organic film, and charge traps at the dielectric/organic interface or at grain boundaries. In our comprehensive experimental and analytical work we demonstrate a method to characterize the charge carrier density in organic thin-film transistors using time-resolved photoluminescence spectroscopy. We developed a numerical model that describes the electrical and optical responses consistently. We determined the densities of free and trapped holes at the interface between the organic layer and the SiO
2
gate dielectric by comparison to electrical measurements. Furthermore by applying fluorescence lifetime imaging microscopy we determine the local charge carrier distribution between source and drain electrodes of the transistor for different biasing conditions. We observe the expected hole density gradient from source to drain electrode.

Keywords: Organic thin-film transistors, charge carrier density, time-resolved photoluminescence spectroscopy, fluorescence lifetime imaging microscopy

1. Introduction

Organic Thin-Film Transistors (OTFTs) form the basis for a wide range of applications in both electronics and optoelectronics [1]. These include electrical logic circuits such as ring oscillators and latches [2], active-matrix driver circuits for LED displays [3], light-emitting-transistors (OLET) [4], optical sensors [5] and bio sensors [6]. For all these devices the charge carrier distribution in the organic semiconductor (OSC) layers is crucial to the output from the device, such as output current or emitted light intensity. Using the gradual channel approximation the local charge density in an OTFT can be approximated by fitting to current-voltage (I-V) measurements [7]. However this approach is to some extent inaccurate since it fails to take into account several factors affecting the local charge density such as charge traps in the OSC as well as the OSC/dielectric interface [8, 9], and injections barriers between the OSC and the electrodes of the transistor [10]. Experimentally there are several approaches to determine the local charge density. Bürgi et al. used scanning Kelvin probe microscopy to extract the local charge density in F8T2 transistors [11]. This approach is rather time consuming being a scanning probe technique and requiring vacuum conditions. Koopman et al. recently used a confocal photoluminescence electro-modulation microscopy method to extract the charge density within the channel of a PTCDI-C13-based OTFT [12]. But this method only takes the photoluminescence (PL) intensity into account leaving the precision of the results vulnerable to bleaching of the OSC.

In this work we demonstrate a method that allows the local charge carrier density to be imaged based on its influence on the local PL lifetime. The PL lifetime from an optically stimulated population of excitons is affected by the presence of polarons through exciton-polaron quenching allowing the local polaron density to be determined from optical measurements. We demonstrate the potential of our method through experimental studies of a model transistor device based on an 5,5-bis(naphthyl)-2,2-bithiophene (NaT
2
) thin film using electrical and optical characterization methods. First, we present experimental results from time-resolved photoluminescence spectroscopy (TR-PLS). These data indicate clearly that the PL lifetime depends on the bias conditions. To determine the local charge density, Bürgi et al. used scanning Kelvin probe microscopy to extract the local charge density in F8T2 transistors [11]. This approach is rather time consuming being a scanning probe technique and requiring vacuum conditions. Koopman et al. recently used a confocal photoluminescence electro-modulation microscopy method to extract the charge density within the channel of a PTCDI-C13-based OTFT [12]. But this method only takes the photoluminescence (PL) intensity into account leaving the precision of the results vulnerable to bleaching of the OSC.

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2. Methods

2.1. Sample preparation

Fig. 1(a) shows the transistor design based on a doped Si substrate acting as the gate electrode with a 300 nm layer of insulating SiO₂ acting as gate dielectric. An interdigitated array of source and drain electrodes is prepared by UV lithography, titanium/gold deposition, and lift-off. Secondly, the contact to the gate electrode is realized by etching through the SiO₂ layer to the underlying Si substrate. Finally, the substrate is covered with a 15 nm layer of NaT₂ deposited by vacuum sublimation. More details about NaT₂ and sample fabrication are given elsewhere [13]. The distance between source and drain electrodes (channel length) is \( d = 40 \mu m \). The sample is designed to fit a standard Zero Insertion Force (ZIF) socket for easy connection to electrical measurement equipment.

2.2. Time-resolved photoluminescence spectroscopy

TR-PLS was conducted with a home-built laser scanning microscope combined with a streak camera system for temporal and spectral resolution as illustrated in Fig. 1(b). The TR-PLS setup utilizes the frequency-doubled output using a commercial second harmonic generator (HarmoniXX, APE) of a Ti:Sapphire laser (Tsunami, Spectra-Physics) with a central wavelength of \( \lambda = 795 \text{ nm} \). The initial repetition rate of 75 MHz is reduced by a pulse picker (pulseSelect, APE) to ca. 4 MHz to match the requirements of the streak camera (Streak scope C10627, Hamamatsu). After passing the laser-scanning setup the beam is focused on the sample using a 40x microscope objective (NA= 0.65). The PL signal is collected either by a CCD camera or by the streak camera. Spectral resolution is achieved by having a spectrometer (SpectraPro SP-2300, Princeton Instruments) in front of the streak camera. This setup enables us to perform time-resolved spectroscopy with a temporal resolution of about 25 ps and with diffraction limited lateral resolution. The data was acquired using the HPDTA software by Hamamatsu.

In order to bias the transistor simultaneously with PL lifetime measurements, we designed a special sample holder: We connected the OTFT via a ZIF socket mounted on a printed circuit board (PCB) of the size of a standard microscope glass slide. We recorded the I-V data using a Labview controlled characterization system based on a National Instruments data acquisition card (DAQ) and voltage and current amplifiers.

2.3. Fluorescence lifetime imaging microscopy

For fluorescence lifetime imaging microscopy (FLIM) we used a custom-built two-photon laser scanning setup based on a Nikon Eclipse Ti microscope and a Mai Tai DeepSee Ti:Sapphire laser (Spectra Physics). The repetition rate was 80 MHz and the central wavelength was set to \( \lambda = 780 \text{ nm} \). The laser light was polarized linearly. We acquired PL lifetime images by time-correlated single-photon counting (TCSPC) using high-speed hybrid detectors (HPM-100-40, Becker&Hickl) with a temporal resolution of about 70 ps. The fluorescence signal passed a multiphoton short-pass filter (700 nm) to block any scattered or reflected laser light. Then the signal was split by a dichroic mirror (long-pass 570 nm) in front of the detectors and further filtered by two band pass filters in front of the detectors (detector 1: \( (607 \pm 40) \text{ nm} \), detector 2: \( (542 \pm 10) \text{ nm} \)) to measure the distinct lifetimes for the two pronounced peaks in the NaT₂ spectrum. The setup is described in detail elsewhere [14] [15]. We used an acousto-optical modulator triggered by the laser-scanning electronics to adjust the laser power and to ensure that the sample is illuminated only during data acquisition. The biasing of the sample is fully software controlled and synchronized with the FLIM acquisition software.

2.4. Numerical model

The PL lifetime is directly related to the exciton lifetime [16]. The exciton lifetime is assumed to be influenced by local charge carriers, which act as quenching centers, and is described through the Stern-Volmer formula [17] [12]:

\[
\frac{1}{\tau} = \frac{1}{\tau_0} + 4\pi D \rho \quad (1)
\]

where \( \tau \) is the exciton lifetime extracted from measurements, \( \tau_0 \) is the exciton lifetime of pristine material, \( r \) is the sum of the exciton and hole radii, \( D \) is the exciton diffusion coefficient, and \( \rho \) is the local charge density that varies at different bias voltages. In order to reveal the values of \( \rho \) and thus interpret the exciton lifetime measurement data, we employed a two-dimensional time-dependent drift-diffusion model to simulate the OTFT device behavior [18]. It was found that a hole-trapping defect can explain the threshold voltage shift and the hysteresis observed in experimental transfer characteristics [19]. In our model, we
assume the hole-trapping defect is located at the interface between NaT$_2$ and SiO$_2$, and the surface-density $\sigma$ of the interface defect can be extracted from the threshold voltage shift $\Delta V_f$ by \cite{20}:

$$\sigma_{ff} = \epsilon \frac{\Delta V_f}{d}$$  \hspace{1cm} (2)

where $\epsilon$ and $d$ are the permittivity and thickness of SiO$_2$, respectively. The holes trapped by the interface defect are not fixed, but follow the Shockley-Read-Hall statistics \cite{20, 21}:

$$\frac{df_i}{dt} = (\sigma_p V_{th} p + \sigma_n V_{th} n) - f_i (\sigma_p V_{th} (p + p_1) + \sigma_n V_{th} (n + n_1))$$  \hspace{1cm} (3)

where $f_i$ is occupation probability of holes trapped by the defect, $V_{th}$ is the carrier thermal velocities, $n$ and $p$ are carrier densities, $\sigma_p$ and $\sigma_n$ are capture cross-section areas, and $n_1$, $p_1$ are defect characteristic density for electrons and holes, respectively. In our analysis, the parameters $\sigma_p$ and $\sigma_n$ are adjusted for fitting the hysteresis amplitudes. The hole mobility can be extracted from the experimental transfer characteristics using the gradual channel approximation \cite{27}. Though, the hole mobility was used as a fitting parameter for matching the transfer characteristics, because in NaT$_2$, the local charge density $\rho$ consists of the free and trapped hole densities. Trapping and de-trapping processes are not taken into account in the gradual channel approximation, but will be quantitatively revealed by the simulation.

3. Results and discussion

Fig. 2 shows experimental TR-PLS results. A streak trace from a pristine NaT$_2$ OTFT is shown in Fig. 2(a). The gate electrode is unbiased ($V_g = 0$ V), while a source-drain voltage of $V_{ds} = -30$ V is applied. The horizontal axis shows the wavelength of the PL photons and the vertical axis shows the arrival time of the photons. The PL decay time of the transistor is very short and most photons arrive within the first nanosecond after laser excitation. However, a time range of 5 ns was chosen for the experiments in order to ensure a proper fitting of the lifetime data. The monitored spectral range is in total from 485 to 575 nm. A temporal integration of the data yields the spectrum of the device as shown in Fig. 2(b). To prevent bleaching effects long exposure times were avoided. Thus the peaks observed earlier from NaT$_2$ thin films \cite{13} are not pronounced. For lifetime analysis we consider one of the main peaks in the NaT$_2$ spectrum from ca. 525 to 545 nm as illustrated by the white lines in Figure 2(a). This region of interest is shown in Figure 2(c). In order to analyze the lifetime we spectrally integrate this data. The resulting decay curve is shown in black. To determine the PL lifetime we performed a two-exponential fit of the intensity decay data $I(t)$ using a Python fitting routine following model:

$$I(t) = A \left[ a_1 \exp \left( -\frac{t}{\tau_1} \right) + a_2 \exp \left( -\frac{t}{\tau_2} \right) \right]$$  \hspace{1cm} (4)

where $\tau_1$ and $\tau_2$ are the time constants and $a_1$ and $a_2$ are the corresponding relative amplitudes and $A$ is the total amplitude. The instrument response function (IRF) was measured separately and considered within the fitting procedure. From the fit we get $\tau_1 = 0.27$ ns and $\tau_2 = 1.26$ ns with a relative amplitude of $a_1 = 68$% of the total amplitude $A$. The error of the fit of the decay times is smaller than 0.02 ns. The fit is shown as red curve in Fig. 2(c). The absolute PL lifetime values are similar to lifetimes reported for other thiophene-based molecules \cite{22}.

After we determined the PL lifetime for $V_g = 0$ V, where we expect no additional charge carriers to be present between the source and the drain electrode, we subsequently applied different gate voltages ($V_g = 0$, $-30$, $-40$ and $-50$ V) at a constant drain-source bias of $V_{ds} = -30$ V. Fig. 2(d) shows the region of interest of the streak trace for $V_g = -50$ V. It is clearly visible that the decay is shorter than for the unbiased sample. This can be explained by the increased presence of charge carriers in the transistor channel. The quantitative analysis of the decay curve yields $\tau_1 = 0.27$ ns and $\tau_2 = 1.08$ ns with a relative amplitude of $a_1 = 72$%. Before describing the results further, we want to note, that it turns out by analyzing the data for various bias settings, that $a_1 = (70 \pm 2)$ % and $\tau_2 = (0.27 \pm 0.01)$ ns. Thus, for the following analysis $\tau_1$ and $a_1$ were fixed to 0.27 ns and 70 %, respectively. The fact, that we observe a fast decay component, that is independent on the sample bias, can be explained by some experimental artefacts like scattering of stray light into the detector. Furthermore, double exponential decays have been also observed earlier, depending strongly on the exact molecular design and the surrounding \cite{23}. However, in the following only relative changes in the lifetime will be considered since they are, according to the model, related to relative changes in the charge carrier density.

The PL lifetime results of the decay component $\tau_2$ for $V_g = 0$, $-30$, $-40$ and $-50$ V, are summarized in Fig. 3. In panel (a) the PL lifetime as a function of the gate voltage is shown as black symbols. The lifetime decreases with decreasing $V_g$ from initially $\tau_2 = 1.25$ ns at $V_g = 0$ V to $\tau_2 = 1.05$ ns at $V_g = -50$ V. For each bias condition, the PL decay data was measured four times before the gate electrode was electrically grounded and a reference PL measurement was made to confirm that no sample degradation had occurred. Between each measurement the sample was moved by approx. 30 $\mu$m within a single channel of the transistor in order to minimize local photo bleaching effects. Previous experiments showed that the PL lifetime is constant within the fitting error of 0.02 ns for several positions within a channel because of the homogeneity of the NaT$_2$ thin film. Only for $V_g = -50$ V a distinct spread of the lifetime is observed, potentially due to local defects in the NaT$_2$ film. These finding give clear evidence that the applied bias results in an induced carrier density that causes photo-exited excitons to recombine faster.

In order to demonstrate the validity of our numerical model we used it to fit the measured the I-V transfer characteristics of the NaT$_2$ OTFT. We obtained I-V curves by measuring the drain current $I_d$ while sweeping the gate voltage $V_g$ from 0 V to $-50$ V and back at a constant drain-source voltage $V_{ds} = -30$ V. The

3
The PL lifetime, shown as black symbols, depends on the gate voltage, i.e. it decreases with decreasing gate voltage. Consequently, a higher mobility is required in the model to fit the measured data. All parameters used in the further analysis are listed in Table 1.

The observed hysteresis is well-known for OTFT [9, 24, 7] and is caused by a shift of the threshold voltage due to trapped charges at the OSC/dielectric interface. This behaviour is in good agreement with OTFT exposed to prolonged bias-stress [25].

According to the gradual channel approximation, we found that the transistor works in the saturated regime and the hole mobilities show only little variation for a gate voltage well above the threshold voltage [26]. In average, the hole mobility is $(1.49 \pm 0.14) \times 10^{-5}$ cm$^2$/V/s. Because of the small standard deviation, it is justified to consider the hole mobility independent of the gate voltage in the further analysis.

The orange curve in Fig. 3(b) shows the modelled drain current calculated by our numerical model. In our fitting procedure we found a hole mobility of $6 \times 10^{-5}$ cm$^2$/V/s, that is around four times higher than the estimate from the gradual channel approximation. We believe that this is due to the fact that during the voltage sweep from the off to the on state of the transistor, the number of trapped holes increase and hence the number of free holes is lower than predicted by the gradual channel approximation. Consequently, a higher mobility is required in the model to fit the measured data. All parameters used in the further analysis are listed in Table 1.

Next to the hole mobility, we found a density of trapped charges at all the depths and all the experimental I-V curve is shown in Fig. 3(b) as black symbols. Because of the small standard deviation, it is justified to consider the hole mobility independent of the gate voltage in the further analysis.

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Table 1: Simulation parameters for OTFT

<table>
<thead>
<tr>
<th>Parameters</th>
<th>Drain/Source (Gold)</th>
<th>Gate (n-Si)</th>
</tr>
</thead>
<tbody>
<tr>
<td>Work function (eV)</td>
<td>5.1</td>
<td>4.1</td>
</tr>
<tr>
<td>NaT2</td>
<td>SiO2</td>
<td></td>
</tr>
<tr>
<td>Relative permittivity</td>
<td>2.36</td>
<td>3.9</td>
</tr>
<tr>
<td>Electron affinity (eV)</td>
<td>2.3</td>
<td>0.95</td>
</tr>
<tr>
<td>Band gap (eV)</td>
<td>2.2</td>
<td>9</td>
</tr>
<tr>
<td>Effective density of states for conduction and valence bands (cm⁻³)</td>
<td>2 x 10²¹</td>
<td>10²²</td>
</tr>
<tr>
<td>Mobility of electrons (cm²/V⁻¹s⁻¹)</td>
<td>10 x 10⁻¹⁰</td>
<td>1</td>
</tr>
<tr>
<td>Mobility of holes (cm²/V⁻¹s⁻¹)</td>
<td>6 x 10⁻⁵</td>
<td>1</td>
</tr>
<tr>
<td>Doping (cm⁻³)</td>
<td>intrinsic</td>
<td>intrinsic</td>
</tr>
</tbody>
</table>

Defect density (cm²) Energy level (eV) Capture cross-section (cm²)  
2 x 10⁻⁵ mid-gap 10⁻²⁷ for electrons 27 10⁻²⁵ for holes

Table 2: Simulated effective free hole density \( \rho_{eff} \) and local charge densities \( \rho_{loc} \).

<table>
<thead>
<tr>
<th>( V_g (V) )</th>
<th>( \rho (cm^{-3}) )</th>
<th>( \rho_{loc} (cm^{-3}) )</th>
</tr>
</thead>
<tbody>
<tr>
<td>0</td>
<td>1.03 x 10⁻⁴</td>
<td>3.38 x 10⁻⁴</td>
</tr>
<tr>
<td>-10</td>
<td>3.76 x 10⁻⁵</td>
<td>3.38 x 10⁻⁷</td>
</tr>
<tr>
<td>-20</td>
<td>4.82 x 10⁻⁵</td>
<td>3.38 x 10⁻⁷</td>
</tr>
<tr>
<td>-30</td>
<td>1.90 x 10⁻⁷</td>
<td>4.26 x 10⁻⁷</td>
</tr>
<tr>
<td>-40</td>
<td>3.95 x 10⁻⁷</td>
<td>7.15 x 10⁻⁷</td>
</tr>
<tr>
<td>-50</td>
<td>6.75 x 10⁻⁷</td>
<td>1.66 x 10⁻⁸</td>
</tr>
</tbody>
</table>

where \( \rho_{loc} \) is the local charge density, \( \rho_{eff} \) is the effective density \( \rho_{eff} \) for each \( V_g \) bias condition when keeping \( V_d = -30 \text{ V} \) (Table 2) and derive the corresponding excitation condition.

In addition to TR-PLS, we used FLIM to study the spatial distribution of the PL lifetime. In the following we used the results of the FLIM detector with the bandpass filter (542 ± 10 nm) in order to be able to compare FLIM and streak results. Fig. 4(a) shows a micrograph of the NaT2 OTFT. The distance between the two electrodes is again 40 μm, the NaT2 film thickness is slightly higher than in case of the TR-PLS experiments (21 nm). The image illustrates the homogeneity of the NaT2 film in-between the source and the drain electrode. A few bright spots are visible, probably caused by some kind of film impurity.

The PL lifetime map for the unbiased device is shown as Fig. 4(b). Here, we are able to use a mono-exponential fit using the same fitting routine as before, taking the instrument response function of the FLIM detection system into account. Before we determined the PL lifetime, we applied a 2-dimensional moving average filter with a filter window of 3x3 px. Due to this, local film impurities, that might act as quenching centres causing a decreased PL lifetime by facilitating radiationless relaxation, appear larger than they are in reality. The spots with short PL lifetimes (shown in green in Fig. 4(b)) seem to correspond to the local defects that are also visible in Fig. 4(a), which are most likely some film impurities.

At the electrodes the PL lifetime is very short (< 500 ns), while in the transistor channel the lifetime is in average \( \tau = 1.25 \text{ ns} \), i.e. the quantitative results are in very good agreement with the TR-PLS lifetime results. In Fig. 4(c) the PL lifetime map of the biased device (\( V_g = -60 \text{ V} \) at \( V_d = -30 \text{ V} \)) is shown using the same colour scale as in panel (b). It is clearly visible that the PL lifetime decreased. The insets (white lines) further show the average lifetime along the x-axis, being constant (in b) but showing a gradient (in c). i.e. the local PL lifetime is a function of the distance to the source electrode.

This effect will be analysed quantitatively in the following. Fig. 4(a) shows the experimental results for \( V_g = 0 \text{ V} \), \( -30 \text{ V} \) and \( -60 \text{ V} \) at constant \( V_d = -30 \text{ V} \). For \( V_g = 0 \text{ V} \) a constant PL lifetime is observed in the transistor channel. As a gate voltage of \( V_g = -30 \text{ V} \) is applied, the PL lifetime is shorter and a gradient of the PL lifetime between drain and source electrode is observed. The shorter PL lifetime is found at the source electrode where the holes are injected into the transistor channel and is related to the local charge carrier density. The PL lifetime gradient becomes more obvious when a gate voltage of \( V_g = -60 \text{ V} \) is applied. The modelled results for \( \tau \) are shown in Fig. 4(b), and are qualitatively in good agreement with the experimental data. For \( V_g = -30 \text{ V} \), a weak increase of the PL lifetime is
visible close to the drain electrode, where it coincidence with the value observed for the unbiased transistor. For \(V_g = -60\) V data the increase is smaller, but still discernible. This effect can be explained by the existence of a depletion zone close to the drain electrode. To illustrate this, Fig. 5(c) shows the free hole density \(p\). The pinch-off should be visible close to the drain electrode, most pronounced for \(V_g = -30\) V, where the hole density drops to approx. \(10 \times 10^{12} \text{ cm}^{-3}\). Similar behaviour is seen also for the other gate voltages, but less pronounced. This trend is in good agreement with our expectations, because the pinch-off should be visible when \(|V_{ds}| \geq |V_g - V_{th}|\). The same feature cannot be observed in the experimental FLIM data in Fig. 5(a).

Most likely, this is due to the limited spatial resolution of the optical system: the depletion zone should extend only around a half microneter into the channel, and our optical system has a resolution of 0.65 μm.

Finally, Fig. 5(d) shows a two-dimensional charge carrier density map \(p(x, z)\) obtained by our model showing the charge distribution in the NaT₂ film within a distance of 5 nm from the substrate/dielectric interface. So far the charge carrier density along the interface normal is not available experimentally and the results can help to optimize the film thickness in stacked organic devices.

4. Summary

In summary, we have shown that optical measurements of the photoluminescence lifetime decay enables us to determine of charge carrier density in organic thin film transistors and other organic electronic devices during operation. We could show that our numerical model describes consistently both the data obtained from electrical device characterization and from optical methods. We confirmed experimentally that the charge carrier density is directly correlated to the PL lifetime change. By applying our numerical model the effective free hole density and the local charge density can be determined from the experimental characterization.

By combining TR-PLS and FLIM it is possible to analyse the charge carrier density with spectral and spatial resolution. The spatial resolution is important because by monitoring the charge carrier density within the device it will be e.g. possible to locate degradation sites of such devices. The spectral resolution will be highly relevant when multilayer or blended organic semiconductor thin films, as used in organic light-emitting devices or organic solar cells, are investigated, where each material has a different spectral response.

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